

PATENT APPLICATION

IN THE U.S. PATENT AND TRADEMARK OFFICE

August 3, 2001

Applicant(s): Toshiaki MOTONAGA et al.

For: HALFTONE PHASE SHIFTING PHOTOMASK AND BLANKS FOR
HALFTONE PHASE SHIFTING PHOTOMASK THEREFOR AND A
METHOD FOR FORMING PATTERN BY USING THE HALFTONE
PHASE SHIFTING PHOTOMASK

Serial No.: 09/825 578 Group: 2622

Filed: April 3, 2001 Examiner: Unknown

International Application No.: N/A

International Filing Date: N/A

Atty. Docket No.: OPS Case 529

Assistant Commissioner for Patents
Washington, DC 20231

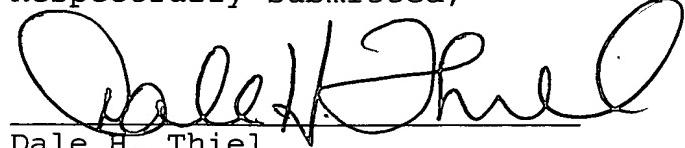
INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the provisions of Rules 1.97(b)(1) and 1.98, enclosed and listed on Form PTO-1449 are the references discussed on pages 1-4 of the application. Also enclosed and listed on Form PTO-1449 are two English-language references corresponding to Japanese Patent No. 58-173744 which is discussed on page 1 of the application.

Further consideration of the application is respectfully solicited.

Respectfully submitted,



Dale H. Thiel

DHT/jp

FLYNN, THIEL, BOUTELL
& TANIS, P.C.
2026 Rambling Road
Kalamazoo, MI 49008-1699
Phone: (616) 381-1156
Fax: (616) 381-5465

FLYNN, THIEL, BOUTELL & TANIS, P.C. 2026 Rambling Road Kalamazoo, MI 49008-1699 Phone: (616) 381-1156 Fax: (616) 381-5465	Dale H. Thiel David G. Boutell Ronald J. Tanis Terrance F. Chapman Mark L. Maki David S. Goldenberg Sidney B. Williams, Jr. Liane L. Churney Brian R. Tumm Tricia R. Cobb	Reg. No. 24 323 Reg. No. 25 072 Reg. No. 22 724 Reg. No. 32 549 Reg. No. 36 589 Reg. No. 31 257 Reg. No. 24 949 Reg. No. 40 694 Reg. No. 36 328 Reg. No. 44 621
--	--	--

Encl: Form PTO-1449 and one copy of each listed reference

